

Notice of References Cited	Application/Control No. 10/573,747		Applicant(s)/Patent Under Reexamination VAN DER SCHAAR ET AL.	
	Examiner Jean B. Corrielus		Art Unit 2611	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-6,480,547	11-2002	Chen et al.	375/240.27
*	C	US-2006/0146934	07-2006	Caglar et al.	375/240.12
*	D	US-7,480,252	01-2009	Van Der Schaar, Mihaela	370/252
*	E	US-7,313,814	12-2007	Zhu et al.	726/6
*	F	US-7,463,683	12-2008	Van Der Schaar et al.	375/240.1
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*	K	US-6,996,173	02-2006	Wu et al.	375/240.1
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)				
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	X					

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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